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APPLICANTS

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** CONTINUING DATA *****

This application is a 371 of PCT/JP03/11971 09/19/2003 *CL*

** FOREIGN APPLICATIONS *****

JAPAN 2002=273709 09/19/2002 *CL*

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 15	TOTAL CLAIMS 20	INDEPENDENT CLAIMS 5
35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met				
Verified and Acknowledged	Examiner's Signature <i>Chung</i> Allowance <i>CL</i>	Initials <i>CL</i>		

ADDRESS

22850

TITLE

Method for forming insulating film on substrate, method for manufacturing semiconductor device and substrate-processing apparatus

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